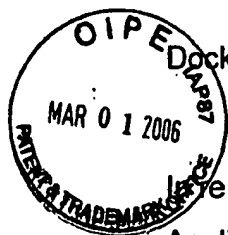


AF/FPW



Docket No. TIP477US

TI-33260

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re **PATENT** application of:

Applicant: Patricia B. Smith et al.
Application No.: 10/647,985
For: POST-ETCH CLEAN PROCESS FOR POROUS LOW
DIELECTRIC CONSTANT MATERIALS
Filing Date: August 28, 2003
Examiner: Zeinab El Arini
Art Unit: 1746

RESPONSE TO OFFICE ACTION DATED DECEMBER 29, 2005

Mail Stop AF
Assistant Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Favorable reconsideration of the above-identified application is respectfully requested in view of the following amendments and remarks.

Enter
ZE 3/14/06